



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant

YEH

Application No.

10/601,701

Filed

June 24, 2002

Title

METHOD FOR FABRICATION

OF **FILM** POLYCRYSTALLINE SILICON THIN

**TRANSISTORS** 

**Group Art Unit** 

2812

Examiner

S. Isaac

Docket No.

BHT/3230-56

MAIL STOP AMENDMENT

Honorable Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

## **AMENDMENT**

Sir:

In response to the Office Action of December 14, 2004, please amend the above-identified application as follows:

Please Entertilos